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PATENT
Customer No. 22,852
Attorney Docket No. 04329.2409

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kei YOSHIKAWA et al.

Application No.: 09/662,219

Filed: September 14, 2000

For: PATTERN CORRECTING
METHOD OF MASK FOR
MANUFACTURING A
SEMICONDUCTOR DEVICE AND
RECORDING MEDIUM HAVING
RECORDED ITS PATTERN
CORRECTING METHOD

)
)
) Group Art Unit: 2623

)
) Examiner: S. Ahmed
)
)

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Technology Center 2600

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Reply to Interview Summary

In response to the Interview Summary dated January 29, 2004, Applicants respectfully submit that Claims 15-17, 19-23, 25-31, and 34-42 correspond to Species I. In view of the foregoing remarks, Applicants respectfully request the reconsideration and reexamination of this application and the timely allowance of the pending claims.

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Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: February 13, 2004

By: 

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